

<b>Search Notes</b> 	<b>Application/Control No.</b>	<b>Applicant(s)/Patent under Reexamination</b>	
	10/029,144	KIM ET AL.	
	<b>Examiner</b> Mike Qi	<b>Art Unit</b> 2871	

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner
349	43 143	8/7/06	208
204	187 192-29 197-35		
205	223		
interference query			